

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Patent Application of)	
)	
Shuzo SATO et al.)	ATT: APPLICATION BRANCH
)	
Serial No. To be assigned)	
)	
Filed: March 8, 2001)	
)	
For: METHODS OF PRODUCING AND)	
POLISHING SEMICONDUCTOR DEVICE)	
AND POLISHING APPARATUS)	

PRELIMINARY AMENDMENT ACCOMPANYING FILING

Commissioner for Patents
Washington, D.C. 20231

Sir:

Prior to the initial examination, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Page 32, line 3, change "Fig. 22" to -- Fig 22A and Fig 22B--

REMARKS

This Preliminary Amendment is requested to accurately identify the drawings. No new matter has been added. Entry of this amendment is requested.

Respectfully submitted,

Date: March 8, 2001



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